

## MAKING METHOD OF MICRO-LENS

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### Abstract

The method for increasing the incident light amount comprises the steps of: a) overlapping the micro lens onto the pixel, which width and length sides are different from each other, in direction of the short side; b) narrowing the short side of the black part rather than the long side to form the clear part; c) reflowing them thermally with a transparent photoresist; and d) forming the micro lens by depositing the photoresist deeply to have the curvature of the long and short axes to be the same.

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